

Notice of References Cited

JUN 19 2006

Application/Control No.

09/830,380

Applicant(s)/Patent Under
Reexamination
ANDRE ET AL.

Examiner

Tamra L. Dicus

Art Unit

1774

Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

INFORMATION DISCLOSURE CITATION
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BREV 13.

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